

Index

- Aberations, 137–139, 146
- Absorption, 282
- Angle scaling, incident, 87, 183
- Arithmetic average, 31–34
- Autocovariance function, 52–55

- Bidirectional reflectance distribution function (BRDF), 19–22
 - PSD calculation from, 85–103
 - surface statistics from (*see* Power spectral density function)
- Bidirectional scatter distribution function (BSDF), 19
 - cosine-corrected, 22
 - data, 295–301
 - data list, 296
 - definition of, 19–22, 140–141
 - and light scatter, 19–22
 - maximum value, 142–143
 - measurement of (*see* Measurements and instrumentation, BSDF)
 - minimum value, 152
 - noise-equivalent (NEBSDF), 138, 152, 154
 - scatterometer components, 133
- Bidirectional transmission distribution function (BTDF), 19
- Bidirectional volume distribution function (BVDF), 19
- BRDF. *See* Bidirectional reflectance distribution function (BRDF)
- Brester's angle, 116
- BSDF. *See* Bidirectional scatter distribution function (BSDF)
- BTDF, 19
- Bulk defects, 16, 220–225
- BVDF, 19

- Calibration, 155
- Chopper blade in scatterometer, 134
- Coblenz sphere, 23
- Complex indices, 120, 285
- Computer disks, 241–245
 - PSDs, 242–244
 - scatter patterns, 242–243
 - texture (roughness), 241, 245
- Conductors, 283

- Constants
 - optical, 120, 285
 - propagation, 277
- Convolution
 - mathematical, 52
 - in receiver, 12, 139
- Coordinate systems, 158
- Cosine-corrected BSDF, 22
- Cross polarization, 211
 - and bulk scatter, 220
 - and defect scatter, 212
 - to improve discrete defect signal to noise, 212
 - and nontopographic defects, 229
 - and surface-roughness scatter, 125, 213
- Curve fittings, 199

- Data format, 295
- Data list, 296
- Defects. *See* Discrete surface and subsurface defects
- Detrending, 49
- Diamond-turned surfaces, 33, 96–102
- Dielectrics, 116–119, 281
- Diffraction
 - from circular aperture, 72
 - general discussion, 59
 - and multiple sinusoids, 75, 292–294
 - from rough surfaces, 188–197
 - from sinusoidal surfaces, 5, 72–74, 287–294
 - from slit aperture, 61–65
- Diffraction theory
 - Kirchhoff, 65–71
 - Rayleigh approach, 77–81
 - verification of, 81
- Diffuse reflectance, 169
- Diffuse samples, 200
- Dipoles, 4, 281
- Discrete surface and subsurface defects, 211
 - bulk defects in transparent optics, 220
 - contaminants and abrupt surface defects, 225
 - nontopographic defects in opaque materials, 229
 - polarization effects, 212
- Dynamic range, 136, 142, 152

- Electromagnetic wave propagation, 275–286
 plane waves
 in conducting medium, 283
 in dielectrics, 281
 in free space, 276
 wave equation, 275
- Electronic noise, 154–155
- Error analysis, 170
- Estimators
 definition of, 39
 of roughness, 40–42
 of PSD, 48–49
 of correlation functions, 53
- Extinction ratio, 216, 217
- Far field, 63
- Fourier optics, 65
- Fourier transforms, 45
- Fractals, 106, 198
- Fraunhofer approximation, 63, 71
- Free space, impedance of, 278
- Fresnel approximation, 63, 71
- Gaussian beams, 142, 278
- Gaussian distribution, 38
- Golden rule, 77
- Goniometers
 in-plane, 135
 out-of-plane, 158
- Grating equation, 7, 73, 75, 291
- Green's theorem, 66
- Haze, 234
- Hemispherical scatter, 158
- Huygens' principle, 61
- Impedance of free space, 278
- Incident angle scaling, 87
- Incident power measurement, 155
- Index of refraction, 114, 281
- Instrument signature, 137–139
 aperture effects on, 139–141
 and near-specular measurements, 143–152
 and noise-equivalent BSDF, 152
- Integrating sphere, diffuse, 169
- Irradiance, 20
- Isotropic surface, two-dimensional, 15, 71, 181
- K-correlation models, 103
- Kirchhoff diffraction theory, 65–71
 from sinusoidal gratings, 287–294
- Light
 polarization of, 111–121
 scattering of, 4–5
- Light point defects (LPD), 233
- Light scatter, 3–27
 and BSDF, 19–22
 and reflector-surface topography, 12–15
 from smooth sinusoidal surface, 5–12
 total integrated, 22–26, 107, 169
 from windows and particulates, 15–17
- Light-scattering events (LSE), 233
- Linear shift invariance, 70
- Lorentzian spectra, 105
- Material signatures, 204
- Measurements and instrumentation, 133–175
 BSDF
 aperture effects on, 139–141
 and electronic noise, 154–155
 measurement error analysis, 170
 noise-equivalent, 154
 of curved optics, 157
 of incident power, 155
 instrument signature, 137
 in large-area optics, 164
 near-specular, 143–152, 180
 of out-of-plane scatter, 158
 raster scans, 161
 reduction of near-specular scatter, 143–152
 near-angle/far-angle boundary, 148
 reflective vs. refractive focusing optics, 145
 scatter measurements, 150
 of retroreflection, 164
 scatterometer components, 133
 with TIS device, 22, 169, 194, 245
- Mie theory, 5
- Near-specular measurements, 143, 170, 180
- NEBSDF. *See* Noise-equivalent BSDF
- Nicodemus, 19
- Noise
 from air particulates, 154
 detector, 154
 electronic, 138, 154
- Noise-equivalent BSDF (NEBSDF), 138, 152
- Nyquist criteria, 39
- Obliquity factor, 69, 78
- One-dimensional surfaces, 13, 29, 90, 104, 186
- Opposition effect, 164

- Optical constants, 120, 285
- Out-of-plane scatter, 158
- Particulate scatter, 15, 225, 233–236
- Polarization, 111, 212
 - concepts, 112
 - of dielectric materials, 281
 - of light, 8, 111
 - of matter, 4, 281
 - Q factor, 78, 86, 121, 213, 217
 - scattering vectors and matrices, 126
- Power measurement, incident, 155
- Power spectral density (PSD) function
 - from profiles, 44–50
 - from scatter data
 - fractal case, 106
 - general case, 85
 - isotropic case, 91
 - K -correlation case, 103
 - Lorentzian case, 105
 - one-dimensional case, 95
 - two-dimensional case, 85, 91
- Poynting vector, 278
- Precision-machined surfaces, 33, 96–102
- Prediction software, 208
- Profiles
 - area, 41
 - deterministic, 31
 - general, 29
 - random, 38
 - sampled, 39
- Profilometers, 29
- Projected solid angle, 20
- Propagation constant, 277
- PSD. *See* Power spectral density (PSD) function
- Q factor, 78, 86, 121–125, 213, 217
- Radiance, 20
- Raster scans, 161
- Rayleigh scatter, 4, 16–18, 153
- Rayleigh smooth-surface limit, 79
- Rayleigh diffraction theory, 77–81
- Rayleigh-Rice perturbation theory, 7, 77
 - conversion to TIS, 107
 - general case, 103, 179
 - isotropic surfaces, 91, 181
 - one-dimensional surfaces, 95, 186
 - and polarization factor (*see* Q factor)
 - predictions using, 177
- Receiver, 133, 150
- Reference detector, 133
- Reference samples, 156
- Reflectance, 116, 169
 - diffuse, 169
- Refraction, index of, 114, 281
- Retroreflection, 164
- Retroscatter, 164
- Root-mean-square (rms), 9, 32–43
- Roughness, 29
- Sample mounts, 134
- Scalar and vector fields, 65
- Scaling
 - by incident angle, 87
 - by wavelength, 87, 157, 181–186
- Scatter
 - from bulk, 15, 220
 - from contamination, 15
 - from defects, 212
 - hemispherical, 158
 - light (*see* Light scatter)
 - measurements (*see* Measurements and instrumentation)
 - from molecules, 17, 153
 - out-of-plane, 158
 - from particulates, 15, 17, 225, 233
 - Rayleigh, 4, 17, 77–81
 - from sinusoidal gratings, 5, 72, 287–294
 - from slits, 61
 - subsurface, 220–225
 - TIS (*see* Total integrated scatter)
 - from windows, 15, 118
- Scatter theory. *See* Diffraction
- Scatter function, 22
- Scatter predictions, 177
 - optical surfaces via Rayleigh-Rice, 178
 - general case, 179
 - isotropic case, 181
 - one-dimensional, 186
 - rough surfaces, 188
 - partial data sets, 197
 - curve fitting, 199
 - fractal surfaces, 198
 - scatter from nonspecular samples, 200
 - Lambertian samples, 201
 - non-Lambertian samples, 204
 - software for, 208
- Scatter specifications, 253–273
 - examples
 - scatterometer focusing mirror, 257
 - imaging optics, 259
 - laser cavity mirrors, 263
 - machined turning mirrors, 267
 - laser range finder, 269
 - silicon surface, 271

- general manufacturing
 - ball bearings, 249
 - emissivity and temperature, 248
 - paper, 246
 - generic, 254
- Semiconductors, 232–241
 - haze, 234–236
 - light point defects, 233
 - light-scattering effects, 233
 - particle scanners, 233
 - particulates, 233–236
 - silicon roughness (scatter)
 - epitaxial surface, 236–239
 - example calculation, 271
 - polished crystal, 236–241
- Slope, 36
- Silicon. *See* Semiconductors
- Smooth-surface criterion, 79
- Snell's law, 115
- Software for scatter predictions, 208
- Spatial filter, 134
- Spatial frequency, 7
- Specifications. *See* Scatter specifications
- Speckle, 141
- Spectra, Lorentzian, 105
- Specular reflectance, 116, 169
- Spheres
 - Coblentz, 22
 - diffuse integrating, 169
- Stylus, 30, 55–57
- Subsurface scatter. *See* Discrete surface and subsurface defects
- Surface roughness, 30
 - profile characterization, 30–44
 - PSD and autocovariance functions, 44–55
 - autocorrelation function, 52–55
 - from the profile, 44–50
 - profile measurement error, 55–57
- Surface statistics from BRDF. *See* Power spectral density (PSD) function
- Surfaces
 - diamond-turned, 33, 96
 - isotropic two-dimensional, 15, 71, 181
 - one-dimensional, 13, 29, 90, 104, 186
 - sinusoidal, 5, 72, 287
 - two-dimensional, 13, 41, 90, 104, 179
- Texture, 241, 245
- TIS. *See* Total integrated scatter
- Tool feed, 33–35, 96
- Tool radius, 33–35
- Topography, 30
- Total integrated scatter (TIS)
 - Coblentz sphere, 22
 - general comments, 22–26
 - integrating sphere, 169
 - Rayleigh-Rice derivation, 107
 - raster scans, 245
 - rough surfaces, 194
- Total internal reflection, 116
- Two-dimensional surfaces, 13, 41, 90, 104, 179
- Uniformity of sample, 161, 245
- Vector or scalar fields, 65
- Wave equation, 275
- Wavelength scaling, 87, 157, 181–186



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